

MK-III

Dual Chamber Plasma Etching System

MK-III is our MK-II times two..... but not twice the footprint. If you need serious production throughput, this system is for you with its dual chambers with 24 levels in each, you can run both chambers simultaneously or by themselves.

Built as an extension of our MK-II platform, the MK-III is the choice of discerning engineers. It offers you the same repeatability, reliability and long life, as well as low maintenance costs.

The two Huge all aluminum chambers accommodate a generously sized active processing surface with its standard configurations of 24 plasma processing levels in each of the dual chambers. Each level, a generous 24" by 18" of usable plasma area.

Processing your boards, whether they be small or large, PTFE, Polyamide or Rigid-Flex you will find that all are uniformly etched by the MK-II, ready for your next production step.

Our system control features an intuitive touch screen interface, controlling every aspect of the plasma process.

Low cost to maintain equates to low cost of ownership.

Rest assured that Plasma Etch will be there for you as long as you own your system.



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Plasma Etch MK-III System Specifications

Standard System Features

Electrode Levels	48 Level System
Electrode Configuration	Horizontal Levels (24" x 18")
R.F. Generator & Matching Network	Dual 5000 Watts Systems
Patented Electrostatic Shielding	
Patented Process Temperature Control	125 ⁰ F to 300 ⁰ F
Mass Flow Controller, 2 Channels Per Chamber	0-2000 CC/Min
Vacuum Gauge	0-10 Torr
Microprocessor System	Touch Screen Control/Multiple Sequence Storage
Vacuum Pump, Oxygen Service	59 CFM
Vacuum Pump Booster Blower	355 CFM
Oil Filtration, Vacuum Pump	3 Microns
Automatic N2 Purging, Vacuum Pump	
Oil Mist Eliminator	
Process Sequence	Dual

Optional System Features

Low Gas Alarms	Up to 4 Channels
Computer Control System w/ Touch Screen	Data Reporting, Event Viewing, Printer
Signal Light Tower	
Dry Vacuum Pump	79/355 CFM
Throttle Vacuum Controller	
Mass Flow Controllers	Up to 4 Channels
Controlled Rate N2 Chamber Purging	
Oil Mist Eliminator	
Custom Chambers and Electrodes	Per Customer Specifications

Optional Facility Equipment

Chilled Water Recirculation	Closed Loop
Fume Scrubber	Packed Bed
Compressed Air Dryer (Purge Gas Generator)	

System Electrical & Mechanical

AC Service, 120 or 208 VAC, 50/60 Hz	100A
System Weight (Plasma Console/Vacuum Pump)	2000/150 lbs.
Footprint, Plasma Console	120 " X 45" X 79"
Footprint, Vacuum Pump	16 " X 30" X 17"

Facility Requirements

AC Service, 120/208 VAC, 50/60 Hz, 3 Phase, 5 Wire	100 Amps
Compressed Air Service 80-100 PSI	<0.5 CFM
System Environment Air Conditioned	85 ⁰ F Maximum
Regulated Process Gases	25-30 PSI
Closed Loop Chilled Water Source	